WPI-AIMR and Fraunhofer ENAS Joint Workshop on Micro Integrated Devices

Date: 2013/02/22 Friday
Place: Aoba Memorial Hall 4th floor (Aobayama Campus, Tohoku University)
(http://www.eng.tohoku.ac.jp/map/?menu=campus&area=c&build=03)

10:00 – 10:10	**Opening Remarks** Director Prof. Motoko Kotani (WPI-AIMR)
NEMS/MEMS and nanomaterial-enhanced passive components (JST-DFG Cooperative Program)	
10:10 – 10:30	**Heterogeneous integration of MEMS and LSI using adhesive bonding** Prof. Masayoshi Esashi (WPI-AIMR) and Prof. Shuji Tanaka (Graduate School of Engineering, Tohoku University)
10:30 – 11:00	**Smart Systems Integration by using Micro- and Nanotechnologies** Prof. Thomas Gessner (Fraunhofer ENAS, Chemnitz University of Technology, WPI-AIMR)
11:00 – 11:25	**Nanomaterial integrated three dimensional inductors** Dr. Yu-Ching Lin (WPI-AIMR)
11:25 – 11:50	**Functional liquids within NEMS/MEMS fabrication** Mr. Felix Gabler (Fraunhofer ENAS, Chemnitz University of Technology)
11:50 – 12:15	**Wafer level bonding of heterogeneous substrates at low temperature** Mr. Jörg Frömel (Fraunhofer ENAS, Chemnitz University of Technology, Fraunhofer Project Center at Tohoku University)
Lunch break	
Functional material integration	
13:30 – 14:00	**[Special Speech] Dealloyed nanoporous metals for device applications** Prof. Mingwei Chen (WPI-AIMR)
14:00 – 14:30	**[Guest Speech] Piezoelectric MEMS mirror with wide scan angle actuated by Nb doped PZT film** Mr. Takayuki Naono (Fujifilm Corporation)
14:30 – 14:50	**MEMS switch using metallic glass thin film** Mr. Yu-Lang Chu (Fraunhofer ENAS, now GI3 Lab of WPI-AIMR)
14:50 – 15:10	**Integration and fabrication of magnetic metallic glass for MEMS mirco-mirror system** Dr. Yao-Chuan Tsai (WPI-AIMR)
15:10 – 15:30	**Fabrication of L10FePt based patterned recording media** Dr. Neelam Kaushik (WPI-AIMR)
Coffee break	
Micro devices and fabrication	
15:45 – 16:15	**[Guest Speech] MEMS Technology challenges for RF-MEMS devices** Dr. Koichi Ikeda (Sony Corporation)
16:15 – 16:35	**Integrated Tactile Sensor Device** Dr. Masanori Muroyama (WPI-AIMR)
16:35 – 16:55	**Local redox cycling-based electrochemical chip device for high-throughput cell analysis** Dr. Kosuke Ino (Graduate School of Environmental Studies, Tohoku University)
16:55 – 17:15	**Microscale technologies to fabricate muscle tissues** Dr. Samad Ahadian (WPI-AIMR)
17:15	**Closing Address** Prof. Masayoshi Esashi
Closing	
18:00 – 20:00	Reception

Language: English | Admission Free | Registration Required for Reception (5000 Yen) by 2013.2.8
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